

1. A silicon p+n junction has doping concentrations of  $N_A = 2 \times 10^{17} \text{ cm}^{-3}$  and  $N_d = 2 \times 10^{15} \text{ cm}^{-3}$ . The cross-sectional area is  $10^{-5} \text{ cm}^2$ . Calculate (a)  $V_{bi}$  and (b) the junction capacitance at (i)  $V_R = 1 \text{ V}$ , (ii)  $V_R = 3 \text{ V}$ , and (iii)  $V_R = 5 \text{ V}$ . (c) Plot  $1/C^2$  versus  $V_R$  and show that the slope can be used to find  $N_d$  and the intercept at the voltage axis yields  $V_{bi}$ .

$$\text{A.) } V_{bi} = (0.025) \ln \left( \frac{2 \times 10^{17} (2 \times 10^{15})}{(1.5 \times 10^{10})^2} \right) = 0.7305 \text{ V.}$$

$$\text{B.) } C = AC = A \sqrt{\frac{e \epsilon_s N_d}{2(V_{bi} + V_R)}} = (10^{-5}) \sqrt{\left[ \frac{1.6 \times 10^{-19}}{2(V_{bi} + V_R)} \right] (11.7)(8.85 \times 10^{-12})(2 \times 10^{15})}$$

$$C = \frac{1.287 \times 10^{-13}}{\sqrt{V_{bi} + V_R}}$$

$$[\text{i}] \quad V_R = 1 \text{ V}$$

$$\therefore C = 9.783 \times 10^{-14} \text{ F}$$

$[\text{ii}]$

$$V_R = 3 \text{ V}$$

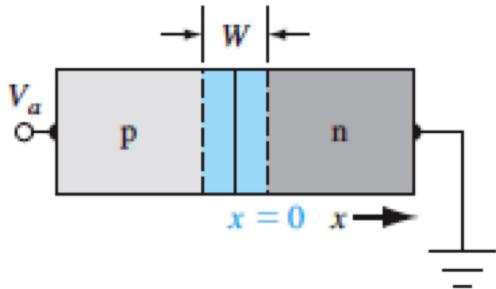
$$\therefore C = 6.563 \times 10^{-14} \text{ F}$$

$[\text{iii}]$

$$V_R = 5 \text{ V}$$

$$\therefore C = 5.376 \times 10^{-14} \text{ F}$$

2. Consider the ideal long silicon pn junction shown in the Figure below.  $T = 300$  K. The n region is doped with  $10^{16}$  donor atoms per  $\text{cm}^3$  and the p region is doped with  $5 \times 10^{16}$  acceptor atoms per  $\text{cm}^3$ . The minority carrier lifetimes are  $\tau_{n0} = 0.05 \mu\text{s}$  and  $\tau_{p0} = 0.01 \mu\text{s}$ . The minority carrier diffusion coefficients are  $D_n = 23 \text{ cm}^2/\text{s}$  and  $D_p = 8 \text{ cm}^2/\text{s}$ . The forward-bias voltage is  $V_a = 0.610 \text{ V}$ . Calculate (a) the excess hole concentration as a function of  $x$  for  $x \geq 0$ , (b) the hole diffusion current density at  $x = 3 \times 10^{-4} \text{ cm}$ , and (c) the electron current density at  $x = 3 \times 10^{-4} \text{ cm}$ .



$$A.) \Delta p_n = p_n - p_{n0} = p_{n0} \left[ \exp\left(\frac{eV_a}{kT}\right) - 1 \right] \exp\left(\frac{-x}{L_p}\right)$$

$$p_{n0} = \frac{n_i^2}{N_d} = \frac{(1.5 \times 10^{10})^2}{10^{16}} = 2.25 \times 10^4 / \text{cm}^3$$

$$L_p = \sqrt{D_p \tau_{p0}} = \sqrt{8(0.01 \times 10^{-4})} = 2.828 \times 10^{-4} \text{ cm}$$

$$\boxed{\Delta p_n = (3.81 \times 10^{14}) \exp\left(\frac{-x}{2.828 \times 10^{-4}}\right) / \text{cm}^3}$$

$$B.) J_p = -e D_p \frac{d(\Delta p_n)}{dx} = \frac{-e D_p (3.808 \times 10^{14})}{2.828 \times 10^{-4}} \exp\left(\frac{-x}{2.828 \times 10^{-4}}\right)$$

$$\text{For } x = 3 \times 10^{-4} \text{ cm}$$

$$J_p = \frac{(1.6 \times 10^{-19})(8)(3.808 \times 10^{14})}{2.828 \times 10^{-4}} \exp\left(\frac{-3}{2.828}\right)$$

$$J_p = 0.5966 \text{ A/cm}^2$$

c.)  $J_{n_0} = \frac{eD_n n_{p_0}}{L_n} \exp\left(\frac{V_a}{V_T}\right)$

$$n_{p_0} = 4.5 \times 10^3 / \text{cm}^3 \quad L_n = 10.72 \mu\text{m}$$

$$J_{n_0} = \frac{(1.6 \times 10^{-19})(23)(4.5 \times 10^3)}{(10.72 \times 10^{-4})} \exp\left(\frac{0.610}{0.0259}\right)$$

$$J_{n_0} = 0.2615 \text{ A/cm}^2$$

3. Consider a GaAs pn junction diode with a cross-sectional area of  $A = 2 \times 10^{-4} \text{ cm}^2$  and doping concentrations of  $N_a = N_d = 7 \times 10^{16} \text{ cm}^{-3}$ . The electron and hole mobility values are  $\mu_n = 5500 \text{ cm}^2/\text{V}\cdot\text{s}$  and  $\mu_p = 220 \text{ cm}^2/\text{V}\cdot\text{s}$ , respectively, and the lifetime values are  $\tau_0 = \tau_{n_0} = \tau_{p_0} = 2 \times 10^{-8} \text{ s}$ . (a) Calculate the ideal diode current at a (i) reverse-biased voltage of  $V_R = 3 \text{ V}$ , (ii) forward-bias voltage of  $V_a = 0.6 \text{ V}$ , (iii) forward-bias voltage of  $V_a = 0.8 \text{ V}$ , and (iv) forward-bias voltage of  $V_a = 1.0 \text{ V}$ . (b) (i) Calculate the generation current at  $V_R = 3 \text{ V}$ . Assuming the recombination current extrapolated to  $V_a = 0$  is  $I_{ro} = 6 \times 10^{-14} \text{ A}$ , determine the generation current at (ii)  $V_a = 0.6 \text{ V}$ , (iii)  $V_a = 0.8 \text{ V}$ , and (iv)  $V_a = 1.0 \text{ V}$ .

$$D_n = \left(\frac{mT}{e}\right)\mu_n = (0.0259)(5500) = 142.5 \text{ cm}^2/\text{s}$$

$$D_p = (0.0259)(220) = 5.70 \text{ cm}^2/\text{s}$$

A.)

c.)  $I_s = A e n_i^2 \left[ \frac{1}{N_a} \sqrt{\frac{D_n}{\tau_{n_0}}} + \frac{1}{N_d} \sqrt{\frac{D_p}{\tau_0}} \right]$

$$[i] I_s = A_{en.} e \left[ \sqrt{\frac{V_n}{\tau_{n0}}} + \sqrt{\frac{V_p}{\tau_{p0}}} \right]$$

$$= (2 \times 10^{-4}) (1.6 \times 10^{19}) (1.8 \times 10^5)^2 \left[ \frac{1}{7 \times 10^{16}} \sqrt{\frac{142.5}{2 \times 10^{-8}}} + \frac{1}{7 \times 10^{16}} \sqrt{\frac{5.70}{2 \times 10^{-8}}} \right]$$

$$I_s = 1.50 \times 10^{-22} A$$

$$[ii] I_0 = I_s \exp \left( \frac{V_{on}}{V_t} \right) = (1.50 \times 10^{-22}) \exp \left( \frac{0.6}{0.0259} \right)$$

$$I_0 = 1.726 \times 10^{-12} A$$

$$[iii] I_0 = (1.50 \times 10^{-22}) \exp \left( \frac{0.8}{0.0259} \right) = 3.896 \times 10^{-9} A$$

$$[iv] I_0 = (1.50 \times 10^{-22}) \exp \left( \frac{1.0}{0.0259} \right) = 8.795 \times 10^{-6} A$$

$$B.) I_{gen} = \frac{A_{en.} W}{2 \tau_0}$$

$$V_b = (0.0259) \ln \left[ \frac{(7 \times 10^{16})(7 \times 10^{16})}{(1.8 \times 10^6)^2} \right] = 1.263 V$$

$$W = \sqrt{\frac{2(10.1)(8.85 \times 10^{-14})(1.263)}{1.6 \times 10^{-19}}} \left[ \frac{7 \times 10^{15} + 7 \times 10^{16}}{(7 \times 10^{16})(7 \times 10^{16})} \right]$$

$$W = 4.201 \times 10^{-5} \text{ cm}$$

[i]

$$I_{\text{gen}} = \frac{(2 \times 10^{-4})(1.6 \times 10^{-19})(1.8 \times 10^5)(4.201 \times 10^{-5})}{2(2 \times 10^{-8})}$$

$$I_{\text{gen}} = 6.049 \times 10^{-14} \text{ A}$$

[ii]

$$I_{\text{rec}} = I_{r_0} \exp\left(\frac{V_a}{2V_t}\right) = (6 \times 10^{-14}) \exp\left(\frac{0.6}{2(0.0259)}\right)$$

$$I_{\text{rec}} = 6.436 \times 10^{-9} \text{ A}$$

[iii]

$$I_{\text{rec}} = (6 \times 10^{-14}) \exp\left(\frac{0.8}{2(0.0259)}\right) = 3.058 \times 10^{-7} \text{ A}$$

[iv]

$$I_{\text{rec}} = (6 \times 10^{-14}) \exp\left(\frac{1.0}{2(0.0259)}\right) = 1.453 \times 10^{-5} \text{ A}$$

4. Consider a silicon PIN photodiode exposed to sunlight. Calculate the intrinsic region width so that at least 90 percent of all photons with wavelengths  $\lambda \leq 1 \mu\text{m}$  are absorbed in the intrinsic region. Neglect any absorption in the p+ or n+ regions.

Minimum  $\alpha$  at  $\lambda = 1 \mu\text{m}$ , yielding  $\alpha = 100/\text{cm}$

$$\frac{\phi(x)}{\phi_0} = e \exp(-\alpha x) = 0.10$$

$$\text{or } \exp(+\alpha x) = \frac{1}{0.10} = 10$$

$$S_0 \propto = \frac{1}{\alpha} \ln(10) = \frac{1}{100} \ln(10) = 2.30 \times 10^{-2} \text{ cm}$$

or 230 μm

5. A MOS device with an aluminum gate is fabricated on a p-type silicon substrate. The oxide thickness is  $t_{ox}=22 \text{ nm} = 220 \text{ Å}$  and the trapped oxide charge is  $Q'_{ss} = 4 \times 10^{10} \text{ cm}^{-2}$ . The measured threshold voltage is  $V_T=+0.45 \text{ V}$ . Determine the p-type doping concentration.

$$C_{ox} = \frac{\epsilon_{ox}}{\epsilon_0} = \frac{(3.9)(8.85 \times 10^{-14})}{220 \times 10^{-8}}$$

$$= 1.569 \times 10^{-7} \text{ F/cm}^2$$

$$Q'_{ss} = (1.6 \times 10^{-19})(4 \times 10^{10}) = 6.4 \times 10^{-9} \text{ C/cm}^2$$

let  $N_a = 4 \times 10^{16} / \text{cm}^3$  via trial and error

$$\phi_{F_p} = (0.0259) \ln \left( \frac{4 \times 10^{16}}{1.5 \times 10^{10}} \right) = 0.3832 \text{ V}$$

$$x_{oT} = \sqrt{\frac{4(11.7)(8.85 \times 10^{-14})(0.3832)}{(1.6 \times 10^{-19})(4 \times 10^{16})}} = 1.575 \times 10^{-5} \text{ cm}$$

$$|Q'_{SD} (\max)| = (1.6 \times 10^{-19})(4 \times 10^{16})(1.575 \times 10^{-5})$$

$$= 1.008 \times 10^{-7} \text{ C/cm}^2$$

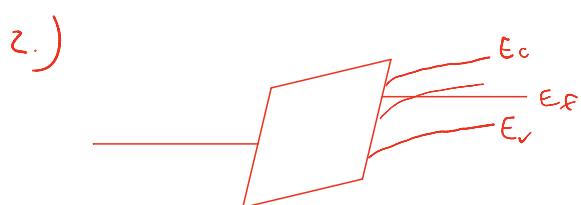
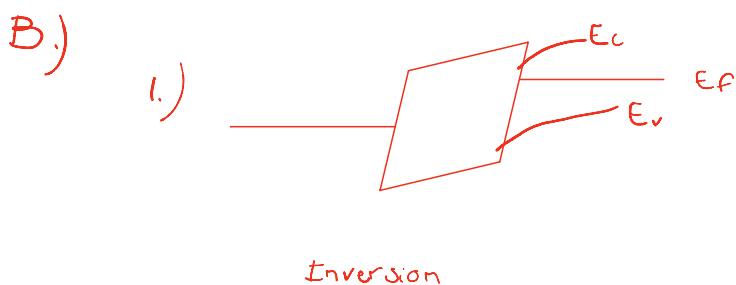
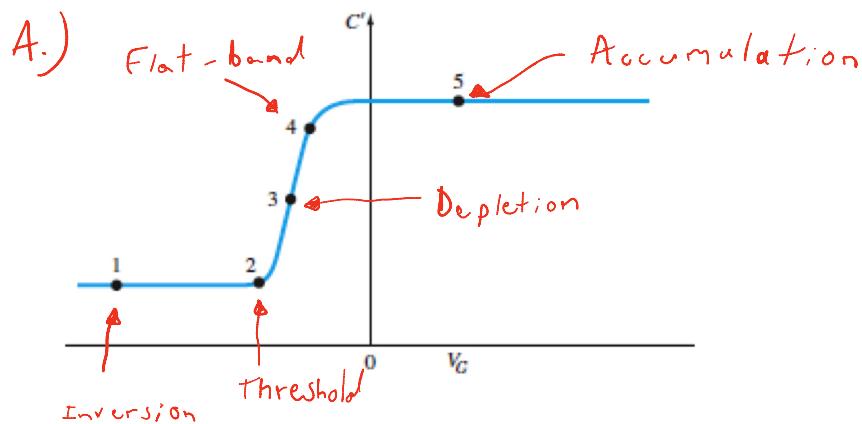
$$\phi_{ms} \approx -0.94 \text{ V}$$

$$V_{TN} = \frac{|Q_{SD}^{'}(\max)| - Q_{SS}^{'}}{C_{ox}} + \phi_{ms} + 2\phi_{F_p}$$

$$= \frac{1.008 \times 10^{-7} - 6.4 \times 10^{-9}}{1.569 \times 10^{-7}} - 0.94 + 2(0.3832)$$

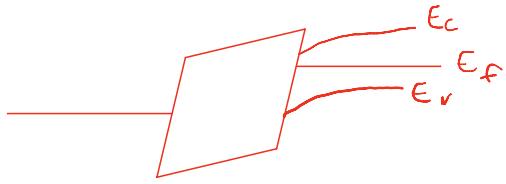
$$V_{TN} = 0.428 \text{ V} \approx 0.45 \text{ V}$$

6. Consider the high-frequency  $C-V$  plot shown in Figure P10.31. (a) Indicate which points correspond to flat-band, inversion, accumulation, threshold, and depletion modes.  
 (b) Sketch the energy-band diagram in the semiconductor for each condition.



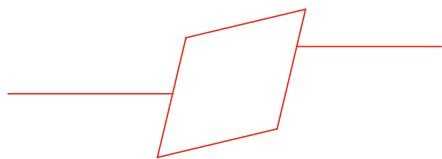
threshold

3.)



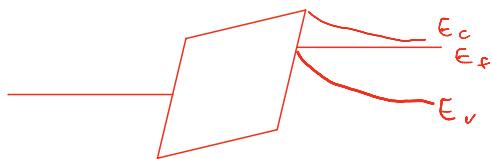
Depletion

4.)



Flat Band

5.)



Accumulation

7. Consider an n-channel MOSFET with the following parameters:  $k_n' = 0.18 \text{ mA/V}^2$ ,  $W/L = 8$ , and  $V_T = 0.4 \text{ V}$ . Determine the drain current  $I_D$  for (a)  $V_{GS} = 0.8 \text{ V}$ ,  $V_{DS} = 0.2 \text{ V}$ ; (b)  $V_{GS} = 0.8 \text{ V}$ ,  $V_{DS} = 1.2 \text{ V}$ ; (c)  $V_{GS} = 0.8 \text{ V}$ ,  $V_{DS} = 2.5 \text{ V}$ ; and (d)  $V_{GS} = 1.2 \text{ V}$ ,  $V_{DS} = 2.5 \text{ V}$

$$\begin{aligned} A) I_D &= \frac{k_n'}{2} \left[ \frac{w}{L} \right] (2(V_{GS} - V_T)V_{DS} - V_{DS}^2) \\ &= \left( \frac{0.18}{2} \right) (8) \left[ 2(0.8 - 0.4)(0.2) - (0.2)^2 \right] \end{aligned}$$

$$= 0.0864 \text{ mA}$$

B.)

$$I_D = \frac{n_n'}{2} \left[ \frac{w}{L} \right] (V_{GS} - V_T)^2$$

$$= \left( \frac{0.18}{2} \right) (8) (0.8 - 0.4)^2$$

$$= 0.1152 \text{ mA}$$

C.)

$$I_D = \frac{n_n'}{2} \left[ \frac{w}{L} \right] (V_{GS} - V_T)^2$$

$$= \left( \frac{0.18}{2} \right) (8) (0.8 - 0.4)^2$$

$$= 0.1152 \text{ mA}$$

( $V_{DS}$  has no effect in this case)

D.)

$$I_D = \frac{n_n'}{2} \left[ \frac{w}{L} \right] (V_{GS} - V_T)^2$$

$$= \left( \frac{0.18}{2} \right) (8) (1.2 - 0.4)^2$$

$$= 0.4608 \text{ mA}$$

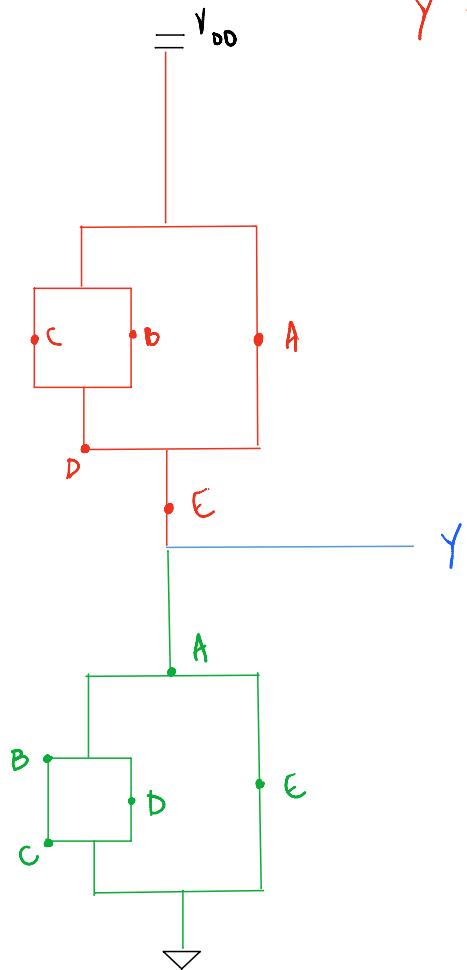
8. (a) Sketch a transistor-level schematic for a single-stage compound CMOS logic gate for the following function:

$$Y = \overline{(A.(C.B + D) + E)}$$

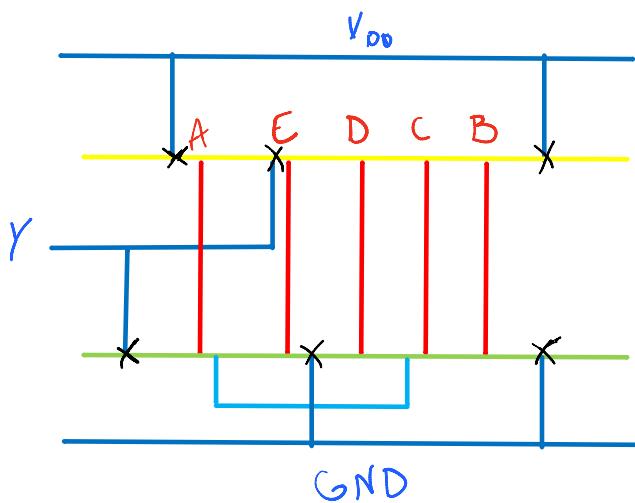
(b) Draw a stick diagram to show the topology of a possible layout

A.)

$$F = A + ((C+B) \cdot D) \cdot E$$



B.)





← Connects drain from A to

